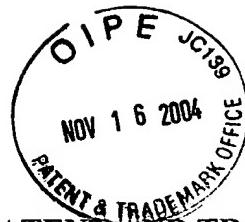


PL  
DOCKET NO.: 2312-0866-2 PCT/smc



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

IN RE APPLICATION OF: Kimihiro MATSUSE, et al.

SERIAL NUMBER: 09/530,588 GROUP: 2814

FILED: May 5, 2000 EXAMINER: QUACH, TUAN N

FOR: METHOD OF FORMING SEMICONDUCTOR WIRING STRUCTURES

**REQUEST TO CORRECT TITLE OF INVENTION**

MAIL STOP ISSUE FEE  
COMMISSIONER FOR PATENTS  
P.O. BOX 1450  
ALEXANDRIA, VA 22313-1450

SIR:

In the matter of the above-identified application for patent, we hereby request correction of your records to reflect the correct title of the invention. The title of the invention should read as follows: **METHOD OF FORMING SEMICONDUCTOR WIRING STRUCTURES.**

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND,  
MAIER & NEUSTADT, P.C.



---

Marvin J. Spivak  
Registration No. 24,913  
Joseph Scafetta, Jr.  
Registration No. 26,803

Customer Number  
**22850**

Tel. (703) 413-3000  
Fax. (703) 413-2220  
(OSMMN 05/04)